

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No. : 09/920,227
Applicant : Ball et al.
Filed : 8/1/2001
Title : METHOD FOR MAKING PHOTOMASK
MATERIAL BY PLASMA INDUCTION
TC/A.U. : 1731
Examiner : Sean Vincent
Docket No. : SP01-193

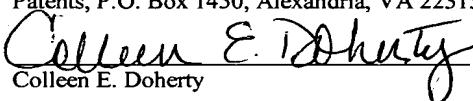
Mail Stop: Non-Fee Amendments
Commissioner for Patents
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Date of Deposit: 2-23-04

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date indicated above with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.


Colleen E. Doherty

AMENDMENT

Sir:

In response to the Office action of October 21, 2003 in the above-captioned patent application, please enter the amendments and remarks as follows:

Amendments to the specification begin on page 2 of this paper;

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper; and

Remarks begin on page 5 of this paper.